NANOSENSORS™
The World Leader in Scanning Probes

2D200

Lateral-(XY)-Calibration Standard

The standard (2D200) is used for a very precise x-y-calibration of the scanning mechanism. The standard consists of a 2-dimensional lattice of inverted square pyramids with 200nm pitch etched into a silicon chip.
A calibration certificate of PTB (Physikalisch Technische Bundesanstalt) is only available on special request. NANOSENSORS™ will mediate a contract between the customer and PTB. Please ask for details.

Features:
- 200 nm pitch
- high accuracy

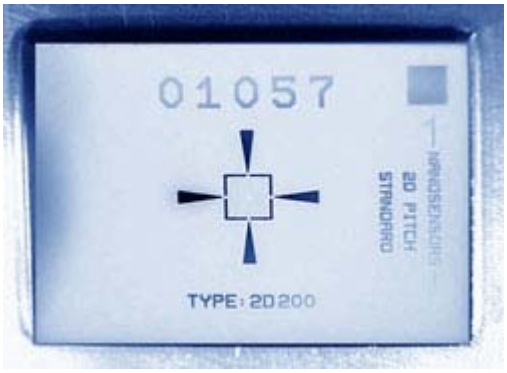
Detailed Specifications:

Chip	
Chip size:	5 x 7 mm2
Active area:	100 x 100 µm2

The active area is located in the center of the chip and is surrounded by the FindMe structure. The lattice of inverted pyramids make up the active area.

Lattice	
Pitch:	200 nm
Accuracy of pyramid position:	10 nm
Accuracy of pitch (10x10µm2 scan):	0.1 %
Accuracy of pitch (100x100µm2 scan):	±0,01 %

Pyramids	
Edge length of square pyramids:	approx. 100 nm
Sidewall angle (versus wafer surface):	54.7°
Accuracy of sidewall angle:	0.5
Depth of pyramids:	(approx. 70 nm)



Order codes and shipping units:

Order Code	Quantity	Data Sheet	Calibration Certificat
2D200	1	enclosed	see above

Please download the datasheet for further information (Adobe PDF format) **ds_2D200.pdf**